PTO/SB/21 (09-04)
Approved for use through 07/31/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE collection of information unless it displays a valid OMB control number. Inder the Paperwork Reduction Act of 1995, no persons are required to respond to a Application Number 10/816,179 Filing Date TRANSMITTAL March 31, 2004 First Named Inventor **FORM** Chung J. Lee Art Unit 1763 **Examiner Name** all correspondence after initial filing)

CO TR	the of	f Pages in This Submission	9+	Attorney Docket Numbe	DSI 30	02						
			ENC	LOSURES (Check	all that apply	ly)						
	Fee Transmittal Form  Fee Attached  Amendment/Reply  After Final  Affidavits/declaration(s)  Extension of Time Request  Express Abandonment Request  Information Disclosure Statement (Supplemental)  Certified Copy of Priority Document(s)  Reply to Missing Parts/ Incomplete Application  Reply to Missing Parts  under 37 CFR 1.52 or 1.53			Drawing(s)  Licensing-related Papers  Petition  Petition to Convert to a  Provisional Application  Power of Attorney, Revoca  Change of Correspondence  Terminal Disclaimer  Request for Refund  CD, Number of CD(s)  Landscape Table on	tion e Address	After Allowance Communication to TC  Appeal Communication to Board of Appeals and Interferences  Appeal Communication to TC (Appeal Notice, Brief, Reply Brief)  Proprietary Information						
		CICNA	TUBE	NE ADDITIONALE ATT	OBNEY (	OD A CENT						
Firm N	ame	Alleman Hall McCoy		& Tuttle LLP	ORNEY, C	OR AGENT						
Signati	ure	M Mat	t Luns	the 4		··································						
Printed	l name	M. Matthews Hall		<del>'</del>	-m·							
Date	Date January 26, 2005				Reg. No.	43,653						
		C	ERTIFIC	CATE OF TRANSMIS	SION/MAI	ILING						
sufficie	nt postage e shown be	as first class mail in an en	velope add			sited with the United States Postal Service with P.O. Box 1450, Alexandria, VA 22313-1450 on						
Typed	or printed r	name Renee Knight	Ü	)		Date January 26, 2005						

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.



In re Application of:

Date: January 26, 2005

CHUNG J. LEE, ATUL KUMAR, CHIEH CHEN and YURI PIKOVSKY

Serial No.

10/816,179

Group Art Unit 1763

Filed

March 31, 2004

For

SYSTEM FOR FORMING COMPOSITE

POLYMER DIELECTRIC FILM

Mail Stop AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Sir:

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §§ 1.56, 1.97, and 1.98

Applicants are submitting this Supplemental Information Disclosure Statement pursuant to 37 C.F.R. §§ 1.56, 1.97, and 1.98 to disclose to the U.S. Patent and Trademark Office the patents, publications, applications, and/or other references listed on the enclosed, completed PTO-1449 form(s). The filing of this Supplemental Information Disclosure Statement should not be construed as a representation that a search has been made or as an admission that the listed references are prior art for this application. Applicants respectfully request that the listed references be expressly considered during prosecution of the application, and that the references be made of record therein and appear among the "references cited" on any patents issuing therefrom.

## **CONTENT OF DISCLOSURE**

This Supplemental Information Disclosure Statement includes (1) six pages of PTO-1449 forms, and (2) a legible copy of each foreign and non-patent reference, if any, listed on the form(s). However, because this application was filed on or after July 1, 2003, no copies of U.S. patents or published U.S. patent applications are included.

## TIMING OF DISCLOSURE / FEE INFORMATION

This Supplemental Information Disclosure Statement is being filed, to the best of the undersigned's knowledge, either (1) before the mailing of a first Office action on the merits, or (2) before the mailing of a first Office action after the filing of a request for continued examination under 37 C.F.R. § 1.114. Therefore, in accordance with 37 C.F.R. § 1.97(b), no fee or statement under 37 C.F.R. § 1.97(e) is required.

Please contact the undersigned with any questions or comments regarding this Supplemental Information Disclosure Statement.

## **CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop AMENDMENT, Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, on January 26, 2005.

Respectfully submitted,

ALLEMAN HALL McCOY RUSSELL & TUTTLE, LLP

M. Matthews Hall

Registration No. 43,653

Customer No. 50488

806 S.W. Broadway, Suite 600

Portland, Oregon 97205

Telephone: (503) 459-4141 Facsimile: (503) 459-4142

Attorney for Assignee

FORM PTO-1449 DOCKET NUMBER APPLICATION NUMBER JAN 2 8 2005 **DSI 302** 10/815,994 INFORMATION DISCLOS **APPLICANTS** CITATION IN A Chung J. Lee et al. FILING DATE **GROUP ART UNIT** March 31, 2004 2827 **U.S. PATENT DOCUMENTS** EXAMINER DOCUMENT NUMBER DATE CLASS NAME SUB FIL. DATE INITIAL CLASS IF APPROP. 3,268,599 08/23/1966 Chow 3,274,267 09/20/1966 Chow 3,280,202 10/18/1966 Gilch 3,288,728 11/29/1966 Gorham 07/25/1967 Chow et al. 3,332,891 3,342,754 09/19/1967 Gorham et al. 3,349,045 10/24/1967 Gilch 3,379,803 04/23/1968 Tittmann et al. 3,503,903 03/31/1970 Shaw et al. FOREIGN PATENT DOCUMENTS DOCUMENT DATE COUNTRY CLASS TRANSLATION SUB NUMBER CLASS YES NO EP 0 349 032 A2 01/03/1990 **EPO** EP 0 523 479 A2 01/20/1993 **EPO** EP 0 856 503 A1 08/05/1998 **EPO** OTHER DOCUMENTS Chow et al., Poly (a,a,a',a'-tetrafluoro-p-xylylene), Journal of Applied Polymer Science, Vol. 13, No. 9, pp. 2325-2332, 1969. Chow et al., The Synthesis of 1,1,2,2,9,9,10,10-octafluorou2, 2Paracyclophane, Journal of Organic Chemistry, Vol. 35, No. 1, pp. 20-22, 1970. Iwamoto et al., Crystal Structure of Poly-p-xylylene. I. The a Form, Jour. Polymer. Sci. Polymer. Phys. Ed., Vol. 11, pp. 2403-2411, 1973. DATE CONSIDERED **EXAMINER** 

FORM PTO-	1449	DOCKET NUMBER DSI 302	UMBER								
	FORMATION DISCI ATION IN AN APPL	APPLICANTS Chung J. Lee et al.									
			FILING DATE March 31, 2004		GROUP ART UNIT 2827						
		U.S. PAT	ENT DOCUMENTS								
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	C	CLASS			DATE PROP.			
	3,509,075	04/28/1970	Niegish et al.								
	3,626,032	12/07/1971	Norris								
	3,694,495	09/26/1972	Norris								
	3,940,530	02/24/1976	Loeb et al.								
	4,117,308	09/26/1978	Boggs et al.								
	4,518,623	05/21/1985	Riley								
	4,823,711	04/25/1989	Kroneberger et al.								
	4,996,010	02/26/1991	Modrek								
	5,142,023	08/25/1992	Gruber et al.								
		FOREIGN P.	ATENT DOCUMEN	ITS							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS		TRANSLAT	TION NC			
(	GB 650 947	03/07/1951	Great Britain								
(	GB 673 651	06/11/1952	Great Britain								
	WO 97/15699	05/01/1997	WIPO								
		OTHE	R DOCUMENTS								
		tation as a Function	g Polymerization of Poly of Temperature, <u>Journal</u>								
	Lee, Transport Polymerization of Gaseous Intermediates and Polymer Crystal Growth, J. Macromol. Sci. Rev. Macromol. Chem., C16(1), p. 79-127, 1977-78.										
		otimizing Poly(chlor No. 7, pp. 1555-15	o-p-Xylelene) or Parylen 65, Sept. 20, 1988.	e C Synt	hesis, <u>Jou</u>	rnal of A	Applied				
EXAMINER			DATE CONSIDERED								

FORM PTO-	1449	DOCKET NUMBER DSI 302					APPLICATION NUMBER 10/815,994						
	FORMATION DISCI ATION IN AN APPL	APPLICANTS Chung J. Lee et al.											
		FILING DATE March 31, 2004			GROUP ART UNIT 2827								
		U.S. PAT	ENT DOCUMENTS	,									
EXAMINER INITIAL	DOCUMENT NUMBER	NAME	NAME					DATE PPROP.					
	5,217,559	06/08/1993	Moslehi et al.										
	5,268,202	12/07/1993	You et al. Stilger et al.										
	5,320,518	06/14/1994											
	5,475,080	12/12/1995	Gruber et al.										
	5,482,009	01/09/1996	Kobayashi et al.										
	5,538,758	07/23/1996	Beach et al.	Beach et al.									
	5,572,884	11/12/1996	Christensen et al.				,,						
	5,639,512	06/17/1997	Nonaka et al.										
	5,648,006	07/15/1997	Min et al.										
		FOREIGN P.	ATENT DOCUMEN	ITS									
	DOCUMENT NUMBER	DATE	COUNTRY CLA			ASS SUB CLASS		TRANSLAT YES					
7	WO 97/15951	05/01/1997	WIPO										
,	WO 97/42356	11/13/1997	WIPO										
7	WO 99/21705	05/06/1999	WIPO										
		OTHE	R DOCUMENTS		<b></b>		•						
	Macromolecular	Science, Part C - Pe	Polyquinoxalines: Tg-Si olymer Reviews (former) r Chemistry and Physics)	y Jour	nal o	f Macro	nolecu						
		Lang, Vapor Deposition of Very low k Polymer Films, Poly (Naphthalene), Poly (Fluorinated Naphthalene), Materials Research Society Symposium Proceedings, Vol. 381, pp. 45-50, April 17,											
	Wary et al., <i>Poly</i> 216, June 1996.	mer Developed to b	e Interlayer Dielectric, <u>S</u>	emi-C	ondu	ctor Inte	rnation	ial, pp.	211-				
EXAMINER			DATE CONSIDERED	DATE CONSIDERED									

FORM PTO-1	449	DOCKET NUMBER DSI 302	APPLICATION NUMBER 10/815,994							
	ORMATION DISCI ATION IN AN APPL	APPLICANTS Chung J. Lee et al.								
			FILING DATE March 31, 2004	GROUP ART UNIT 2827						
		U.S. PAT	ENT DOCUMENTS	S						
EXAMINER INITIAL	DOCUMENT NUMBER	NAME		CLASS	UB ASS	L. DATE APPROP.				
	5,879,808	03/09/1999	Wary et al.							
	5,945,170	08/31/1999	Kozak et al.							
	5,958,510	09/28/1999	Sivaramakrisham							
	6,051,321	04/18/2000	Lee et al.							
	6,130,171	10/10/2000	Gomi							
	6,140,456	10/31/2000	Foggiator							
	6,144,802	11/07/2000	Kim							
	6,265,320	07/24/2001	Shi et al.							
	6,302,874	10/16/2001	Zhang							
		FOREIGN P.	ATENT DOCUMEN	VTS						
	DOCUMENT NUMBER	DATE	COUNTRY		SUB LASS	TRANSLATION YES NO				
V	WO 99/21706	05/06/1999	WIPO							
V	WO 99/21924	05/06/1999	WIPO							
V	WO 99/22043	05/06/1999	WIPO							
		OTHE	R DOCUMENTS							
	Wunderlick, <i>Cry</i> 246-247, 1996.	stal Nucleation, Gro	owth, Annealing, Macror	nolecu	lar Phys	ics, V	ol. 1-2	, pp. 2	242-243,	
	Greiner, Poly(1,4-xylylene)s: Polymer Films by Chemical Vapour Deposition, Trends in Polymer Science, Vol. 5, No. 1, pp. 12-16, 1997.									
	Harrus et al., Parylene Af-4: A Low e <sub>R</sub> Material Candidate for ULSI Multilevel Interconnect Applications, Material Research Society Symposium Proceedings, Vol. 443, 1997.									
EXAMINER			DATE CONSIDERED							

FORM PTO-1449				DOCKET NUMBER DSI 302			APPLICATION NUMBER 10/815,994						
	FORMATION DISCLO TATION IN AN APPLI		APPLICANTS Chung J. Lee et al.										
		FILING DATE March 31, 2004				GROUP ART UNIT 2827							
		U.S. PAT	EN	T DOCUMENTS					<u> </u>				
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME				CLASS		SUB CLASS		IL. DATE APPROP.		
	6,703,462	03/09/2004	L	ee									
	6,797,343	09/28/2004	L	ee									
	2002/0050659	To	oreki et al.										
	2002/0120083	Lee											
	2003/0051662	03/20/2003	L	ee									
	2003/0072947	04/17/2003	L	ee									
	2003/0143341	07/31/2003	L	ee									
	2003-0188683	10/9/2003	L	ee									
	2003-0195312	10/16/2003	Le	ee									
		FOREIGN P.	ATI	ENT DOCUMEN	TS		• • •		<del></del>				
	DOCUMENT NUMBER	DATE	COUNTRY CL					UB LASS YE		TRANSLATION S NO			
		OTHE	R D	OCUMENTS									
				aditions on the Prope sium Proceedings, V							ene Af-4		
	Ryan et al., Effect of Deposition and Annealing on the Thermomechanical Properties of Parylene Films, Material Research Society Symposium Proceedings, Vol. 476, pp. 225-230, 1997.												
	Yang et al., High I 385-390, 1998.	aryle	ne Films, Journal of	Cryst	al Gr	owth	, Vol	l. 183	, No. 3	3, pp.			
	Mathur et al., Vapo Research, Vol. 14,			ene-F Using Hydrogo 999.	en as	Carr	ier G	as, <u>J</u>	ourna	<u>l of M</u>	<u>laterials</u>		
EXAMINER			DATE CONSIDERED										

FORM PTO-1449			DOCKET NUMBER APPLICATION NUMBER 10/815,994							ER		
	FORMATION DISCLO ATION IN AN APPLIC	APPLICANTS Chung J. Lee et al.										
		FILING DATE March 31, 2004				GROUP ART UNIT 2827						
		U.S. PAT	EN.	T DOCUMENTS								
EXAMINER INITIAL				NAME							IL. DATE APPROP.	
_	2003-0198578	10/23/2003	Le	ee								
	2003-0196680 10/23/2003			Lee				_				
			<u> </u>									
			<u> </u>									
			ļ									
			-									
			ļ									
		FOREIGN PA	ATF	ENT DOCUMEN	TS				<b>,</b>			
	DOCUMENT	DATE	1	COUNTRY CLA						TRANSLATION		
	NUMBER		+				CLASS		YE:	S	NO	
			+	· · · · · · · · · · · · · · · · · · ·								
			+-									
		OTHE	R D	OCUMENTS	<u></u>							
		phological Transi	tions	in Fluorinated and s, Vol. 565, pp. 297-				d Pa	rylen	es, M	aterial_	
				, Semiconductor Inte		-		, Fet	oruary	y <b>20</b> 00	).	
				l Energy Partitioning 113, No. 17, pp. 714				todis	socia	ition o	f Halon	
	Rashed, Properties POCO Graphite In		ics o	f Silicon Carbide, w	ebsite	publ	icatio	on ( <u>w</u>	/ww.j	oco.c	om),	
EXAMINER				DATE CONSIDERED								